

Based on Form PTO-1449 (3/90) LIST OF REFERENCES CITED BY APPLICANT (Use several sheets if necessary)				ATTY. DOCKET NO. 930008-2183		SERIAL NO. Not Yet Assigned	
				APPLICANT Elèni BERDERMANN and Wim DE BOER			
				FILING DATE Not Yet Assigned		GROUP Not Yet Assigned	

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA	3,665,193	05/23/1972	Kozlov et al.			
	AB	5,773,830	06/30/1998	Lu et al.			

FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	AC							

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)			
	AD		HAN S K ET AL.: "Fabrication and testing of a microstrip particle detector based on highly oriented diamond films" DIAMOND AND RELATED MATERIALS, ELSEVIER SCIENCE PUBLISHERS, AMSTERDAM, NL, vol. 9, no. 3-6, April 2000 (2000-04), pages 1008-1012.
	AE		SOUW E-K ET AL.: "Response of CVD diamond detectors to alpha radiation" NUCLEAR INSTRUMENTS & METHODS IN PHYSICS SPECTROMETERS, DETECTORS AND ASSOCIATED EQUIPMENT, NORTH-HOLLAND PUBLISHING COMPANY, AMSTERDAM, NL, vol. 400, no. 1, November 21, 1997, pages 69-86.
	AF		WANG S G ET AL.: "Investigation on polycrystalline CVD diamond-based alpha-particle detectors" MATERIALS RESEARCH BULLETIN, ELSEVIER SCIENCE PUBLISHING, NEW YORK, US, vol. 37, no. 6, May 2002, pages 1033-1040.
	AG		KRAMMER M ET AL.: "CVD diamond sensors for charged particle detection" DIAMOND AND RELATED MATERIALS, ELSEVIER SCIENCE PUBLISHERS, AMSTERDAM, NL, vol. 10, no. 9-10, September 2001, pages 1778-1782.
	AH		BAUER C ET AL.: "Recent results on chemical-vapor-deposited diamond microstrip detectors" NUCLEAR INSTRUMENTS & METHODS IN PHYSICS RESEARCH, SECTION - A: ACCELERATORS, SPECTROMETERS, DETECTORS AND ASSOCIATED EQUIPMENT, NORTH-HOLLAND PUBLISHING COMPANY, AMSTERDAM, NL, vol. 380, no. 1-2, October 1, 1996, pages 183-185.
	AI		

EXAMINER	DATE CONSIDERED
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* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.